

**ROCHESTER INSTITUTE OF TECHNOLOGY  
MICROELECTRONIC ENGINEERING**

# **Pictures of John Galt Chip at Each Step in the Submicron CMOS Process**

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**Program webpage: <http://www.microe.rit.edu>**

## *INSTRUCTIONS FOR TAKING PICTURES*

- Process step photos **needed** (topography changes)
  - PH03 OX--**, **ET--**, **CV--**, **ME01**
- Process step photos **not needed** (topography does not change)
  - Steps 1-5**, **CL01**, **IM01**, **DE01**, **SI01**, etc.
- Use **Leica Microscope** attached to PC in **Lithography Bay 1**
  - Magnification**
    - 2.5X for Steps 6-18 - Wells and well implant steps
    - 10X + for Steps 19-End
  - Viewing Area**
    - 3 Images for Steps 6-18**
      - Small NMOS/PMOS , Big NMOS/PMOS , Ring Oscillator
    - Steps 19-End will need many images** to show small features
- Use **Osprey Software** to capture image
  - Center** desired area in image viewer
  - Ctrl+P** to take snapshot
- Use **Microsoft Power Point** to document images
  - Do not alter contrast/brightness/etc
  - Label image with what it is and magnification used
  - Insert process purpose in first slide for each step

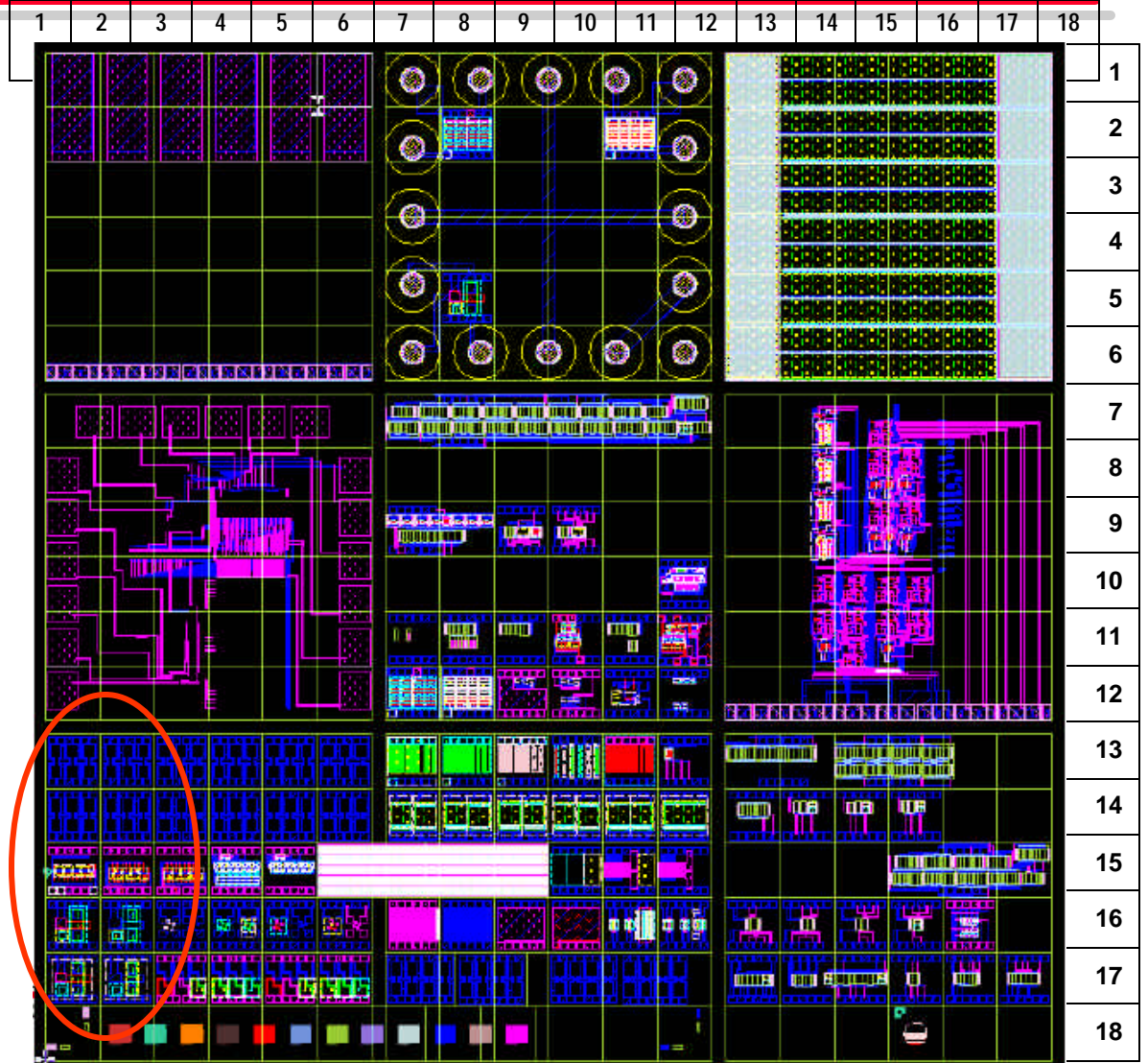
## SUB-CMOS 150 PROCESS

### SUB-CMOS Versions 150

- |                               |                               |                                |                                |
|-------------------------------|-------------------------------|--------------------------------|--------------------------------|
| 1. ID01 -scribe               | 21. ET07 – Branson Asher      | 41. PH03 – 5 – poly            | 61. CV03 – TEOS, 5000A         |
| 2. DE01 – 4pt probe           | 22. PH03 – 3 - p-well stop    | 42. ET08 – LAM 490             | 62. PH03 – 10 CC               |
| 3. CL01 – RCA Clean           | 23. IM01- stop B11            | 43. ET07 – Branson Asher       | 63. ET06 – Drytek Quad / BOE   |
| 4. OX05--- pad oxide, Tube 4  | 24. ET07- Branson Asher       | 44. PH03 – 6 - n-LDD           | 64. ET07 – Branson Asher       |
| 5. CV02- 1500 Å               | 25. CL01 – RCA Clean          | 45. IM01 – LDD P31             | 65. CL01 Special - Two HF Dips |
| 6. PH03 –1- n well            | 26. OX04 – field, Tube 1      | 46. ET07 – Branson Asher       | 66. ME01- CVC 601              |
| 7. ET29 – LAM490              | 27. ET19 – Hot Phos           | 47. PH03 – 7 - p-LDD           | 67. PH03 -11- metal            |
| 8. IM01 – n-well P31          | 28. ET06 – BOE                | 48. IM01 – LDD B11             | 68. ET15 – plasma Etch Al      |
| 9. ET07 – Branson Asher       | 29. OX04 – Kooi, Tube 1       | 49. ET07 – Branson Asher       | 69. ET07 – Solvent + Asher     |
| 10. CL01 – RCA Clean          | 30. IM01 – Blanket Vt         | 50. CL01- RCA Clean            | 70. SI01 – Sinter Tube 2       |
| 11. OX04 – well oxide, Tube 1 | 31. PH03 – 4 - PMOS Vt Adjust | 51. CV03 –TEOS, 5000A          | 71. CV03 – TEOS- 5000Å         |
| 12. ET19 – Hot Phos           | 32. IM01 – Vt- B11            | 52. ET10 – Drytek Quad         | 72. PH03 – VIA                 |
| 13. IM01 – p-well B11         | 33. ET07 – Branson Asher      | 53. PH03 – 8 - N+D/S           | 73. ET06 – Drytek Quad / BOE   |
| 14. OX06 – well drive, Tube 1 | 34. ET06 - BOE                | 54. IM01 – N+D/S P31           | 74. ET07- Strip Resist         |
| 15. ET06 - BOE                | 35. CL01 – RCA Clean          | 55. ET07 – Branson Asher       | 75. ME01- PE 2800              |
| 16. CL01 – RCA Clean          | 36. OX06 – gate, Tube 4       | 56. PH03 – 9 P+ D/S            | 76. PH03 - M2                  |
| 17. OX05 – pad oxide, Tube 4  | 37. CV01 – Poly 5000A         | 57. IM01 – P+ D/S B11          | 77. ET15 -plasma Etch Al       |
| 18. CV02 - 3500 Å             | 38. IM01 - dope poly          | 58. ET07 – Branson Asher       | 78. ET07 – Solvent + Asher     |
| 19. PH03 – 2 - Active         | 39. OX08 – Anneal, Tube 3     | 59. CL01 Special - No HF Dip   | 79. SEM1 - pictures            |
| 20. ET29 – LAM 490            | 40. DE01 – 4pt probe          | 60. OX08 – DS Anneal, Tube 2,3 | 80. TE01                       |
|                               |                               |                                | 81. TE02                       |
|                               |                               |                                | 82. TE03                       |
|                               |                               |                                | 83. TE04                       |

8-16-09

# JOHN GALT PRODUCT



**Areas of interest**

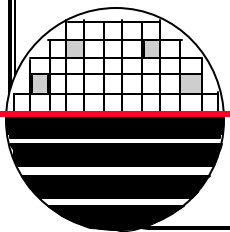
SMALL NMOSFET →

SMALL PMOSFET →

RING OSCILLATOR →

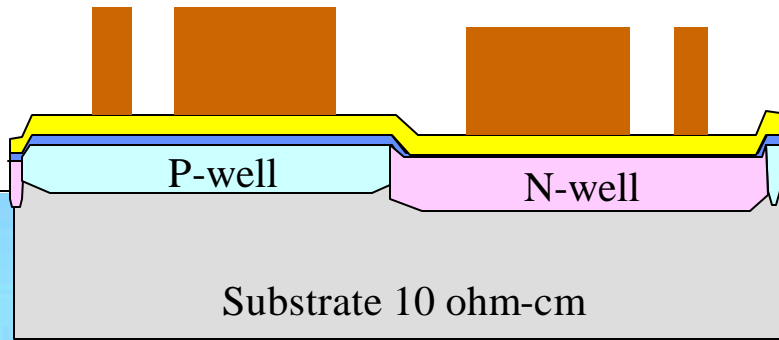
BIG NMOSFET →

BIG PMOSFET →



# STEP 19 – PH03 LEVEL 2 ACTIVE

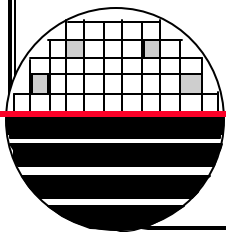
## SMALL NMOS / PMOS



SMALL NMOS  
Column 1 – Row 13



SMALL PMOS  
Column 1 – Row 14

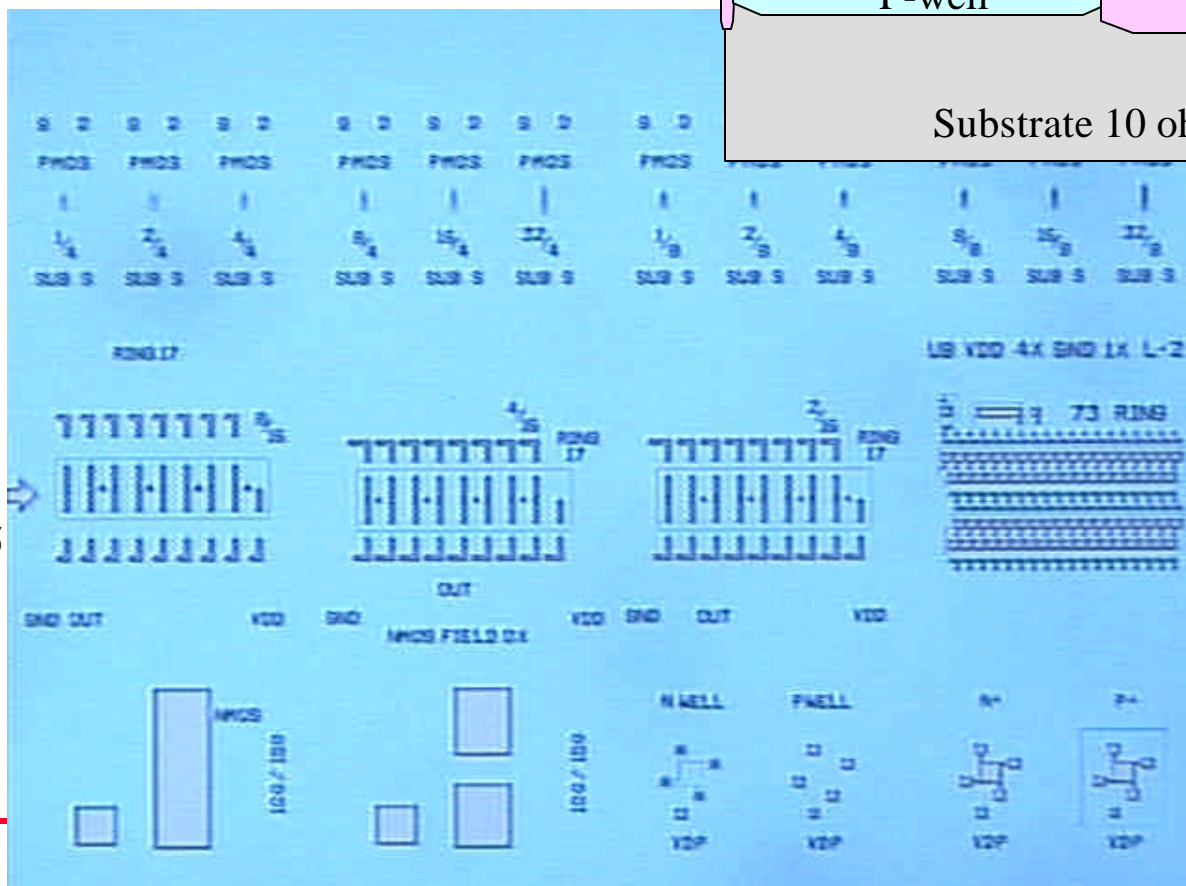
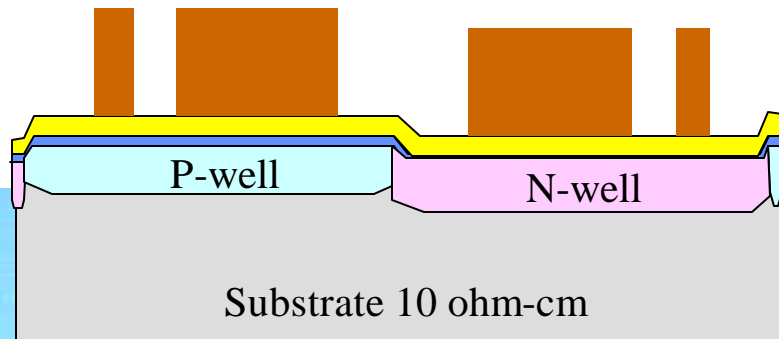


Mag = 2.5X

PLAY

**STEP 19 – PH03 LEVEL 2 ACTIVE**

**RING OSCILLATOR**



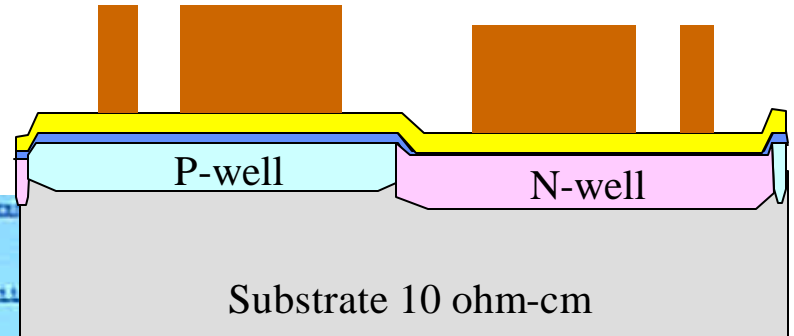
Ring Oscillator  
Column 1 – Row 15

Mag = 2.5X

**PLAY**

**STEP 19 – PH03 LEVEL 2 ACTIVE**

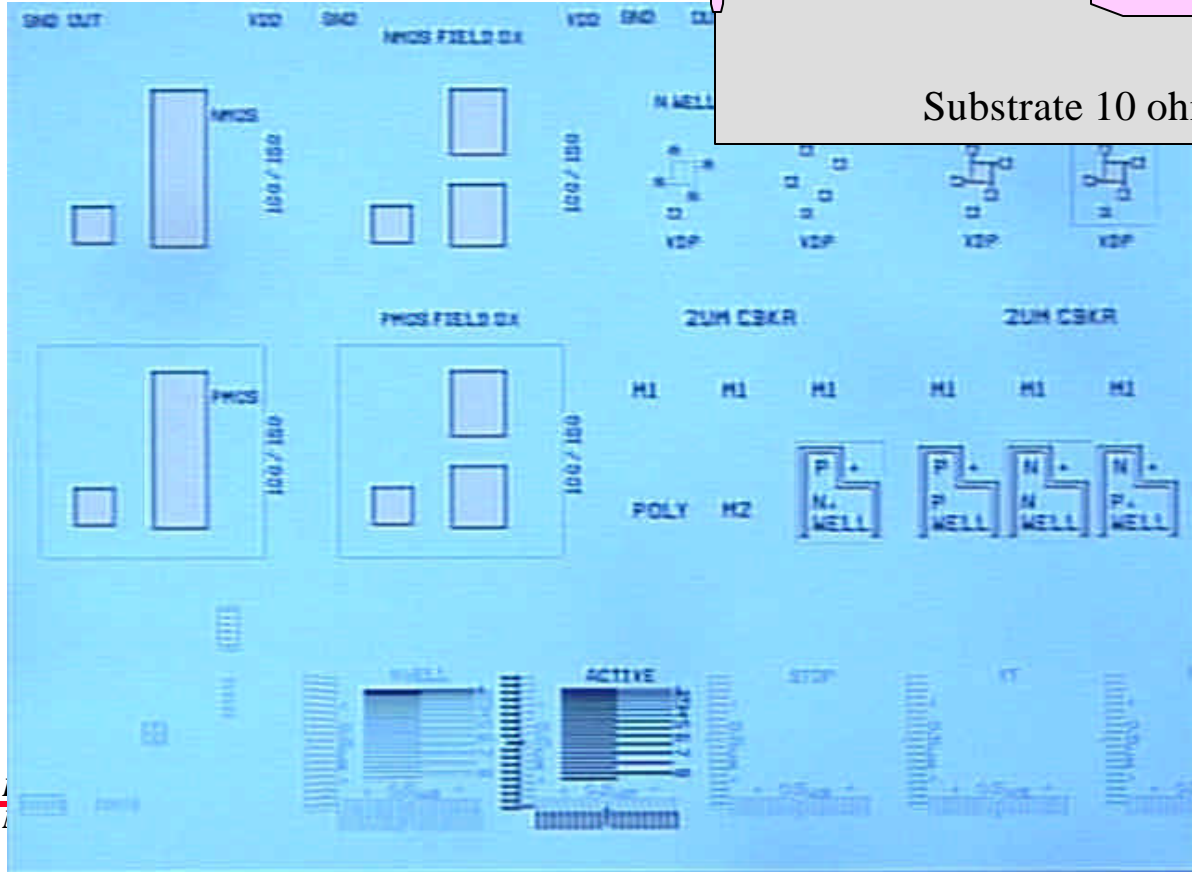
**BIG NMOS / PMOS**



BIG NMOS  
Column 1 – Row 16

BIG PMOS  
Column 1 – Row 17

Alignment marks  
Column 1 – Row 18

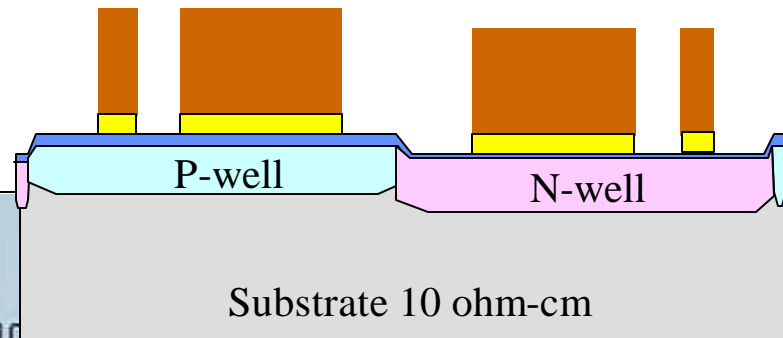


Mag = 2.5X

**PLAY**

# STEP 20 – ET29 NITRIDE ETCH

## SMALL NMOS / PMOS



SMALL NMOS  
Column 1 – Row 13

G	D	G	D	G	D	G			
NMOS		NMOS		NMOS		NMOS	NMOS	NMOS	
!		!		!		!	!	!	
1/4		2/4		4/4		8/4	16/4	32/4	
SUB S		SUB S		SUB S		SUB S	SUB S	SUB S	

SMALL PMOS  
Column 1 – Row 14

G	D	G	D	G	D	G	D	G	D
PMOS		PMOS		PMOS		PMOS	PMOS	PMOS	
!		!		!		!	!	!	
1/4		2/4		4/4		8/4	16/4	32/4	
SUB S		SUB S		SUB S		SUB S	SUB S	SUB S	

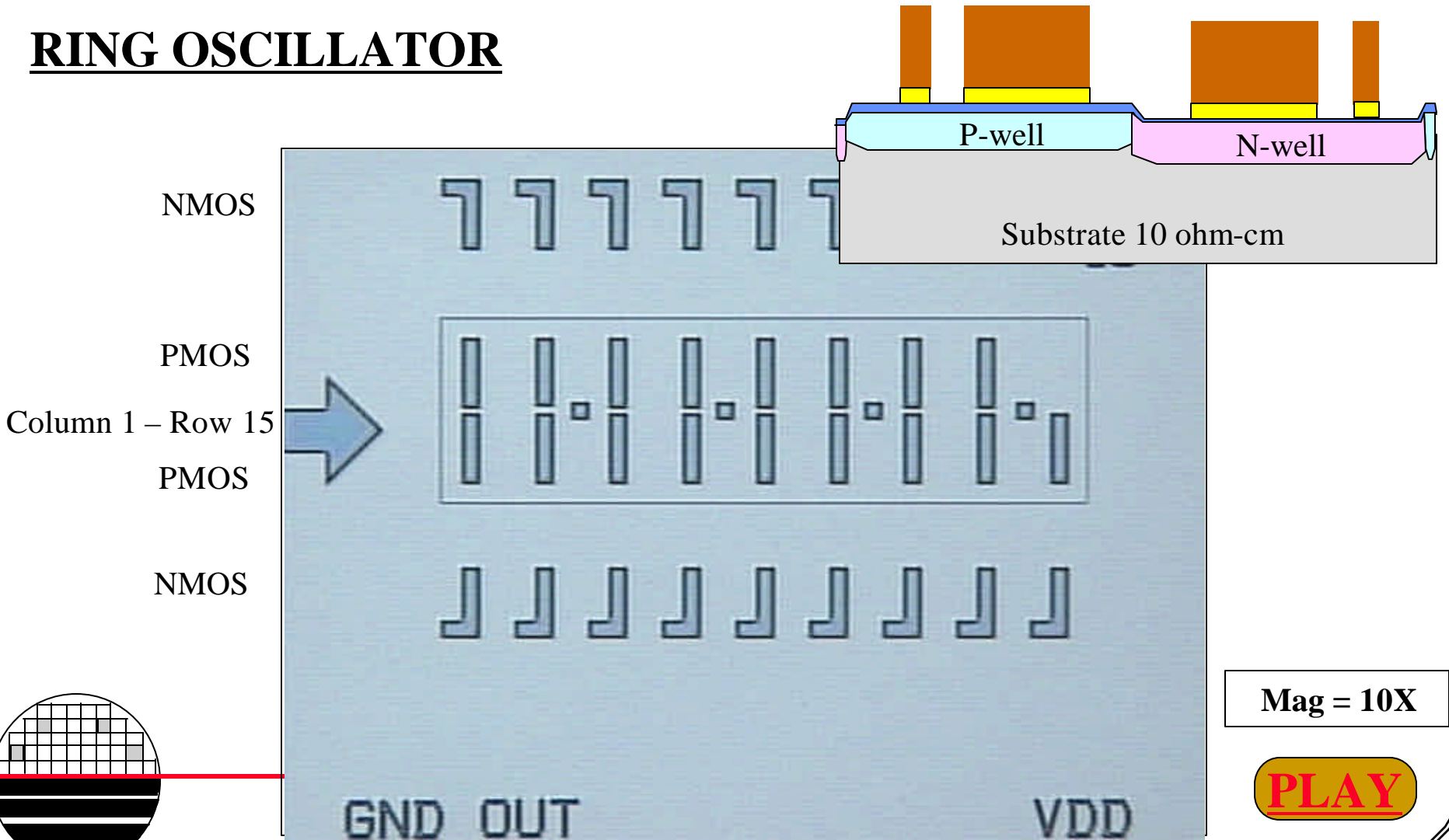
Mag = 10X

**PLAY**



# STEP 20 – ET29 NITRIDE ETCH

## RING OSCILLATOR

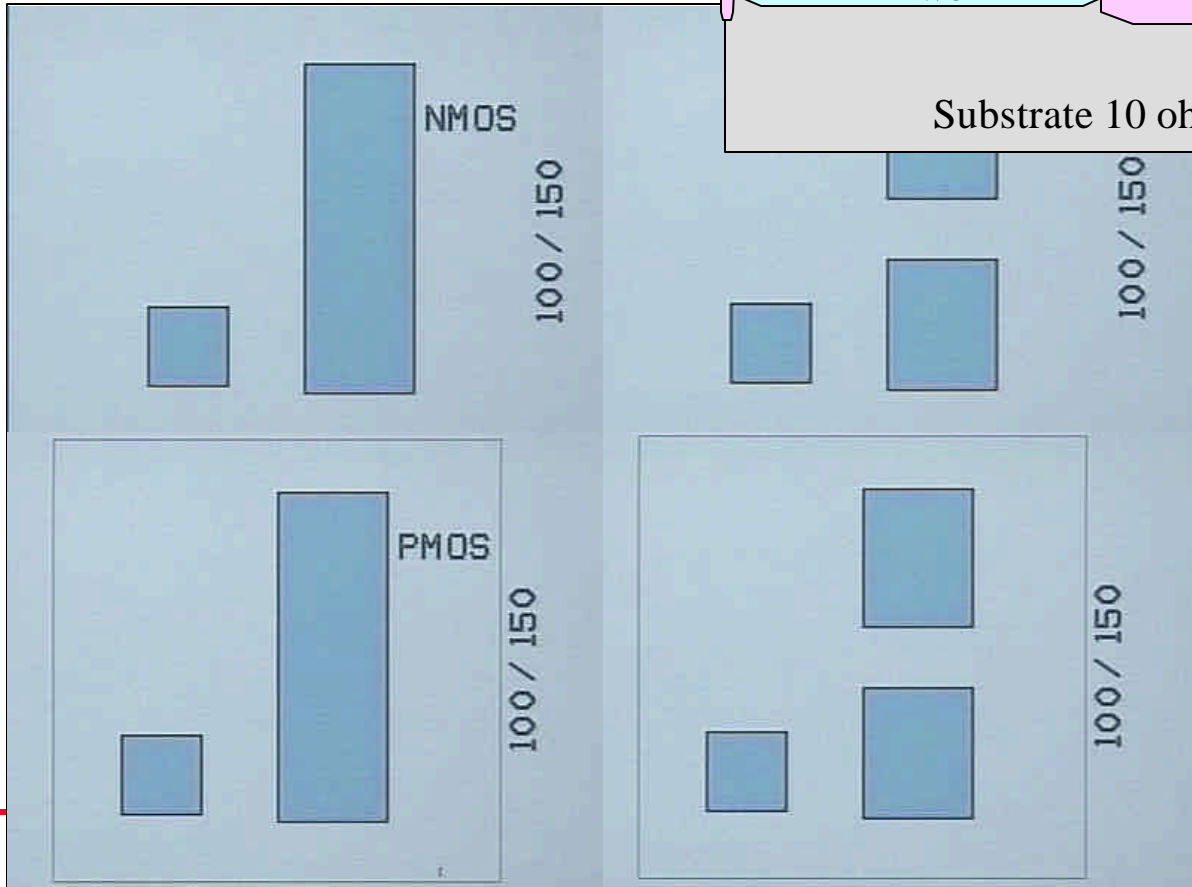
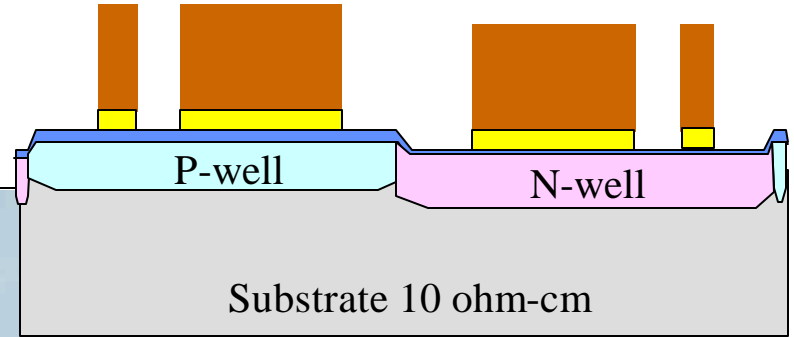


Mag = 10X

**PLAY**

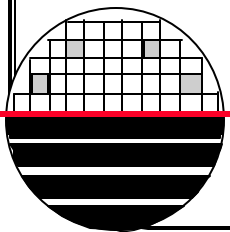
# STEP 20 – ET29 NITRIDE ETCH

## BIG NMOS / PMOS



BIG NMOS  
Column 1 – Row 16

BIG PMOS  
Column 1 – Row 17

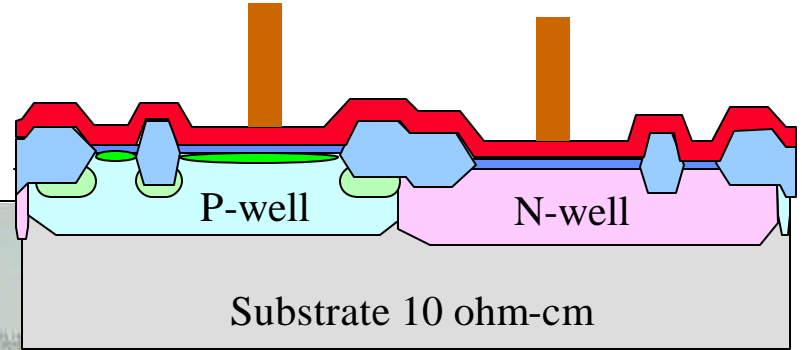


Mag = 10X

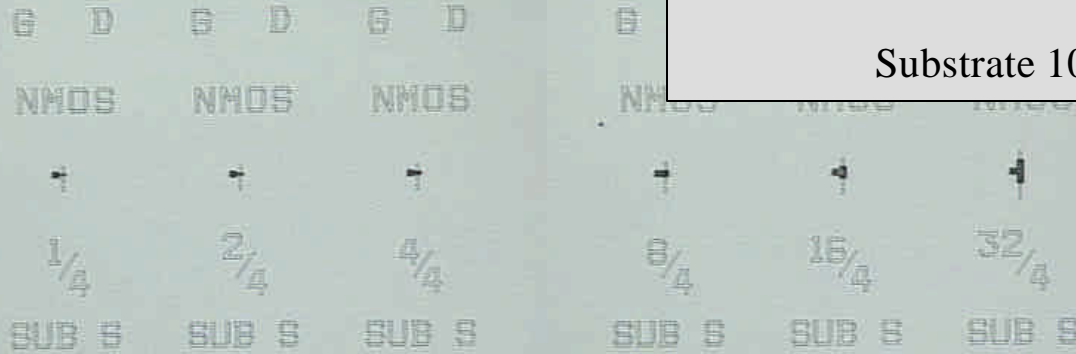
**PLAY**

# STEP 41 – PH03 LEVEL 5 - POLY

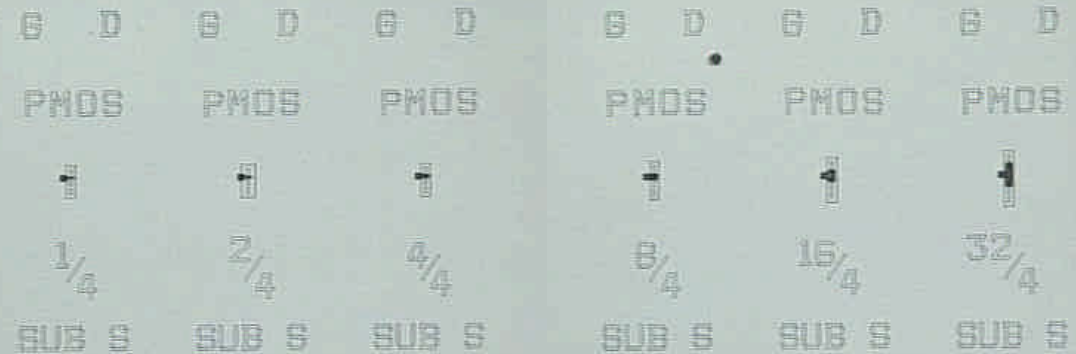
## SMALL NMOS / PMOS



SMALL NMOS  
Column 1 – Row 13



SMALL PMOS  
Column 1 – Row 14



Mag = 10X

PLAY

**STEP 41 – PH03 LEVEL 5 - POLY**

**RING OSCILLATOR**

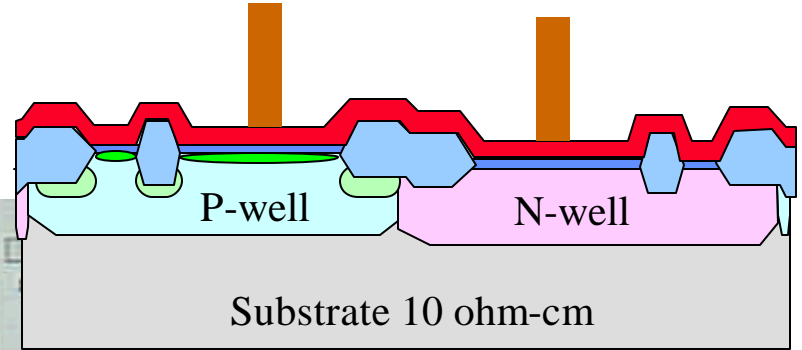
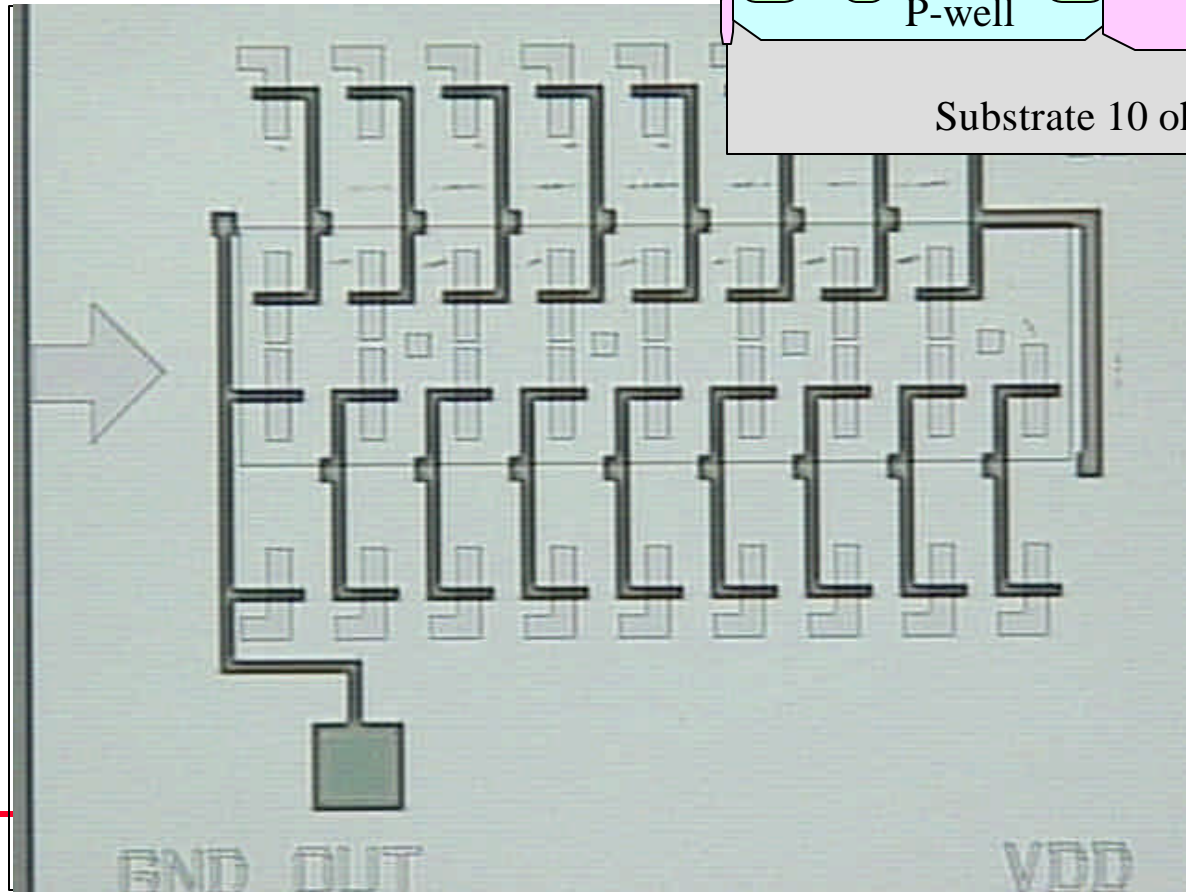
NMOS

PMOS

Column 1 – Row 15

PMOS

NMOS

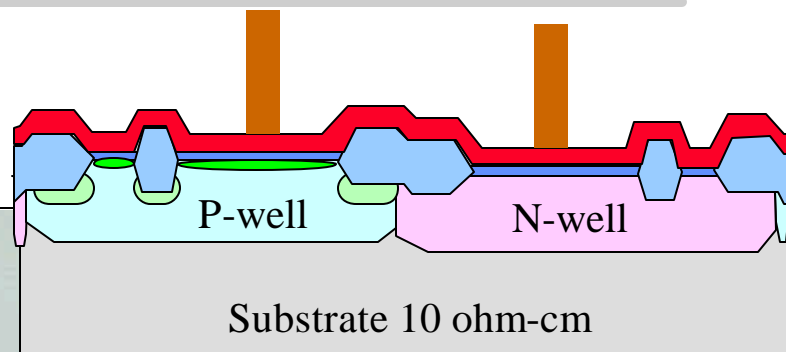


Mag = 10X

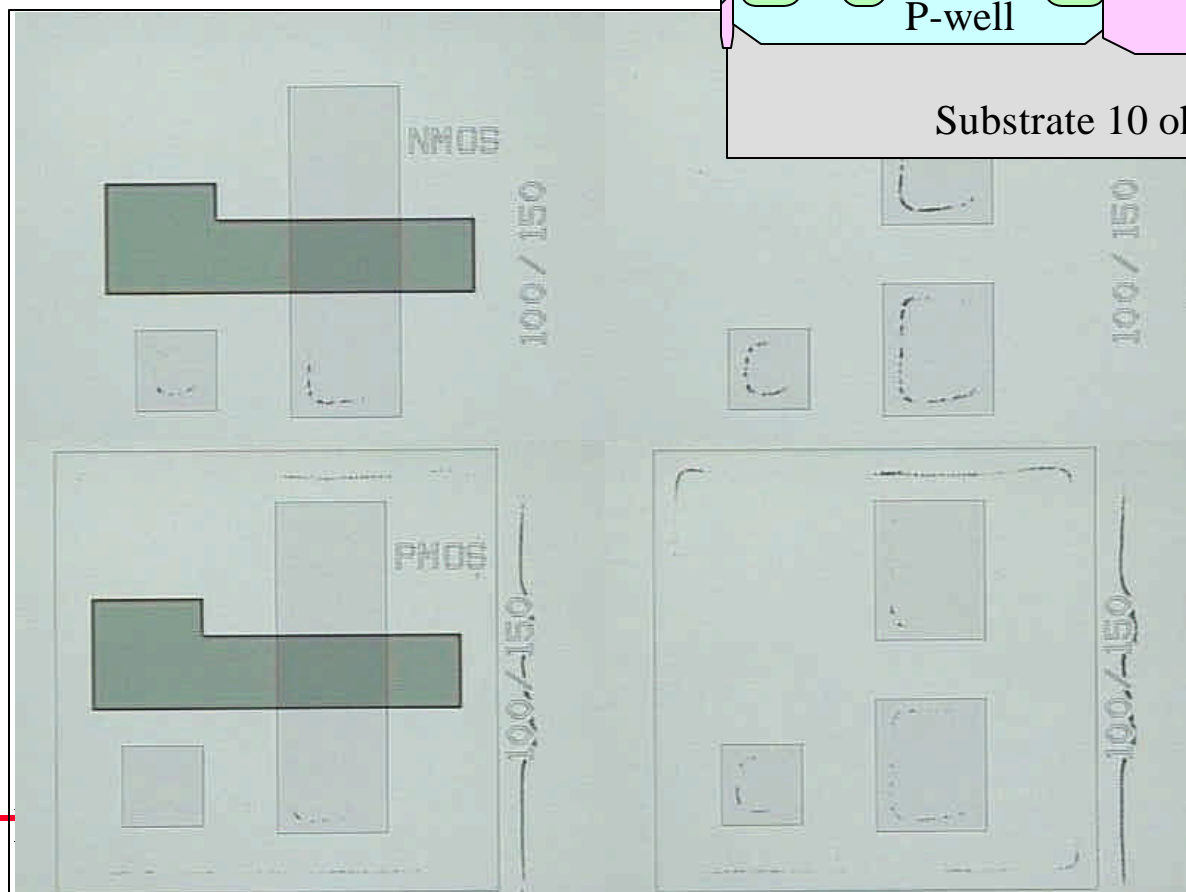
**PLAY**

**STEP 41 – PH03 LEVEL 5 - POLY**

**BIG NMOS / PMOS**



BIG NMOS  
Column 1 – Row 16



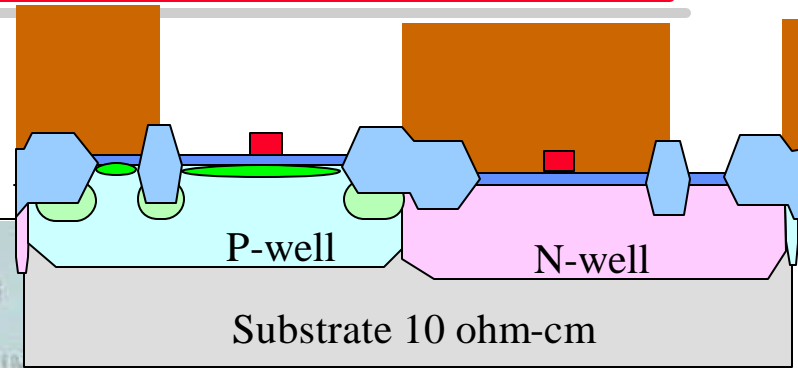
BIG PMOS  
Column 1 – Row 17

Mag = 10X

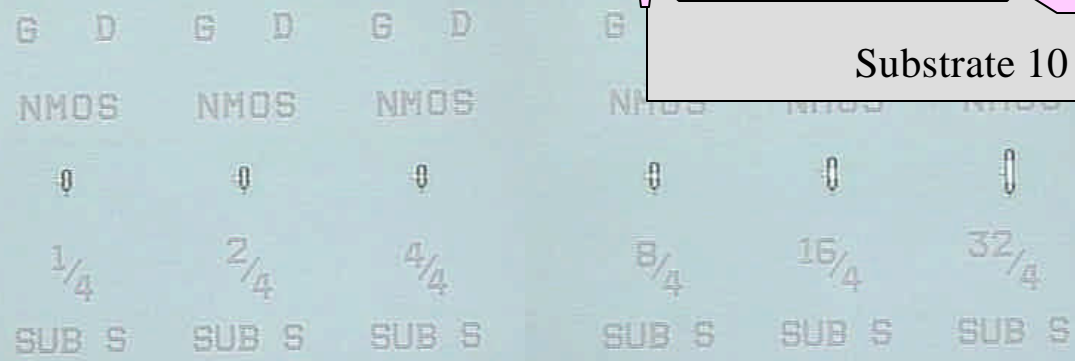
**PLAY**

# STEP 44 – PH03 – LEVEL 6 – N-LDD

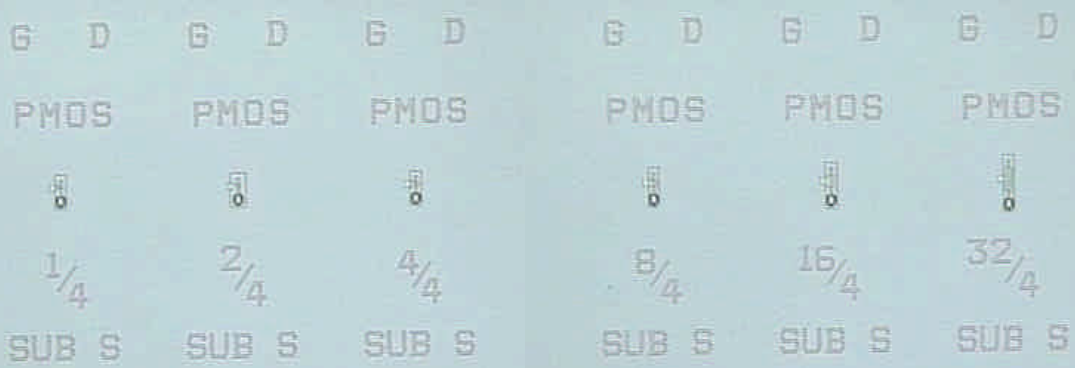
## SMALL NMOS / PMOS



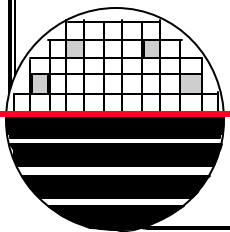
SMALL NMOS  
Column 1 – Row 13



SMALL PMOS  
Column 1 – Row 14



Mag = 10X



**STEP 44 – PH03 – LEVEL 6 – N-LDD**

**RING OSCILLATOR**

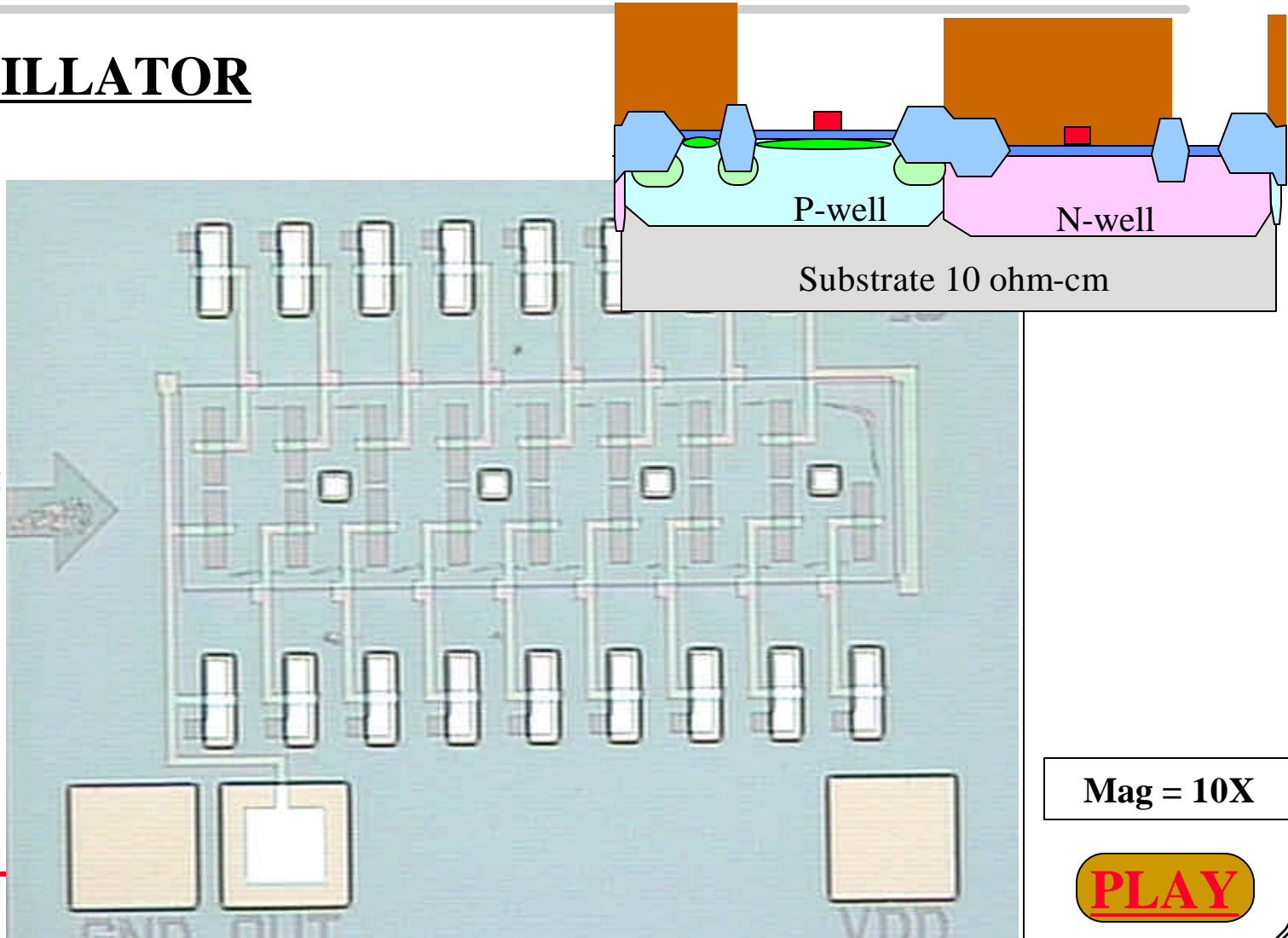
NMOS

PMOS

Column 1 – Row 15

PMOS

NMOS

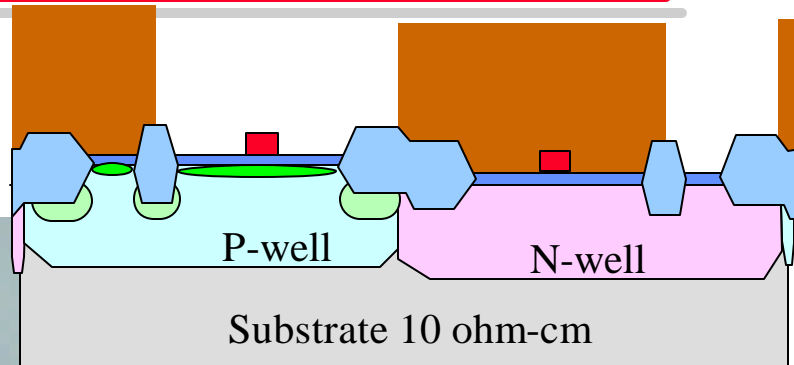


Mag = 10X

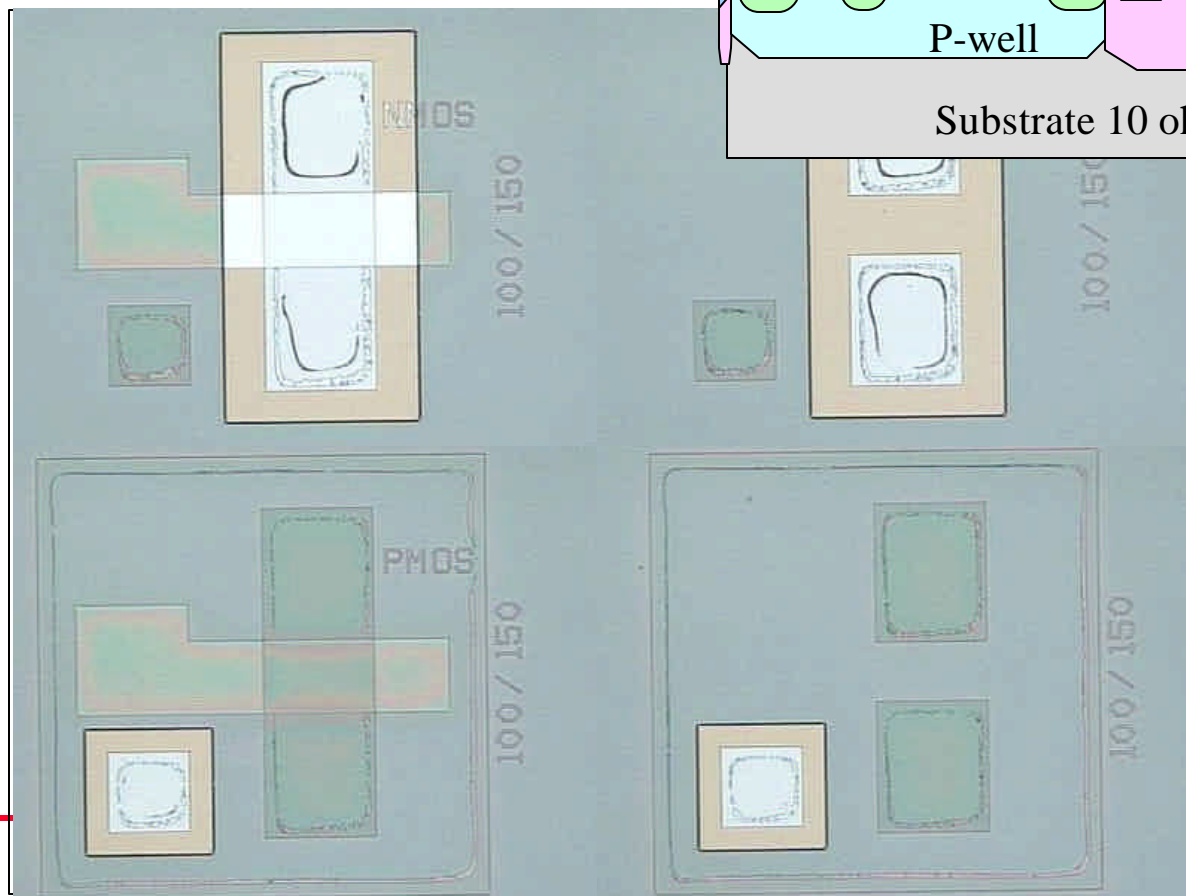
**PLAY**

**STEP 44 – PH03 – LEVEL 6 – N-LDD**

**BIG NMOS / PMOS**



BIG NMOS  
Column 1 – Row 16



BIG PMOS  
Column 1 – Row 17

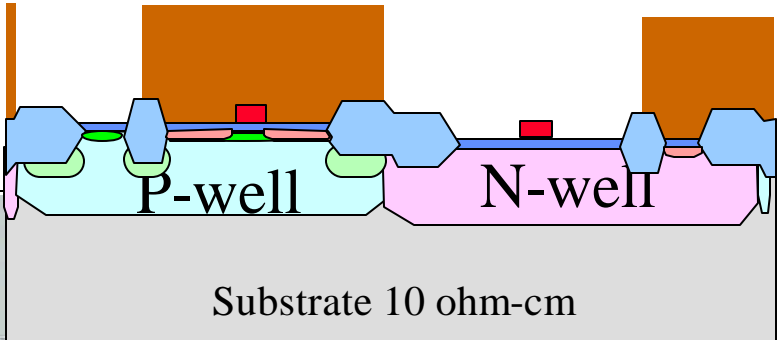
Mag = 10X

**PLAY**

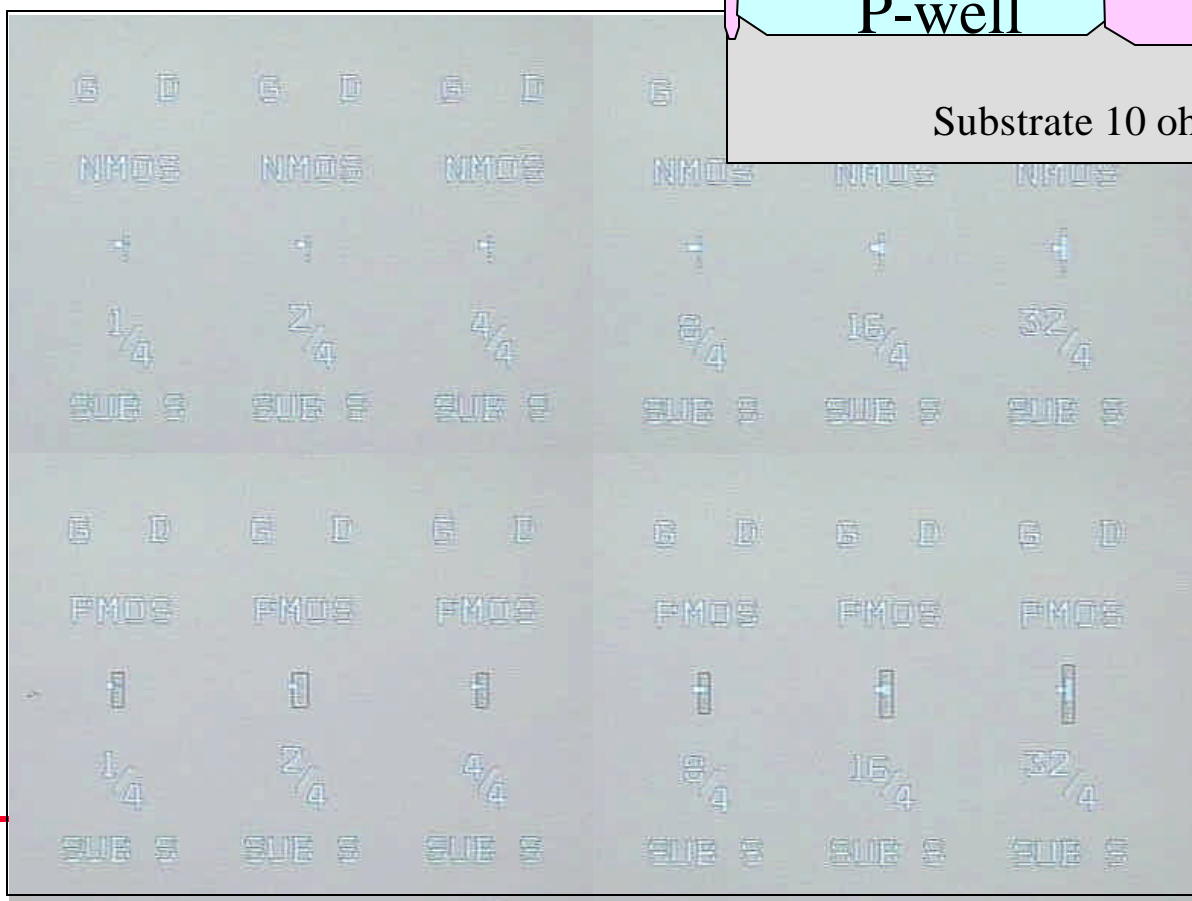


# STEP 47 – PH03 LEVEL 7 P-LDD

## SMALL NMOS / PMOS



SMALL NMOS  
Column 1 – Row 13



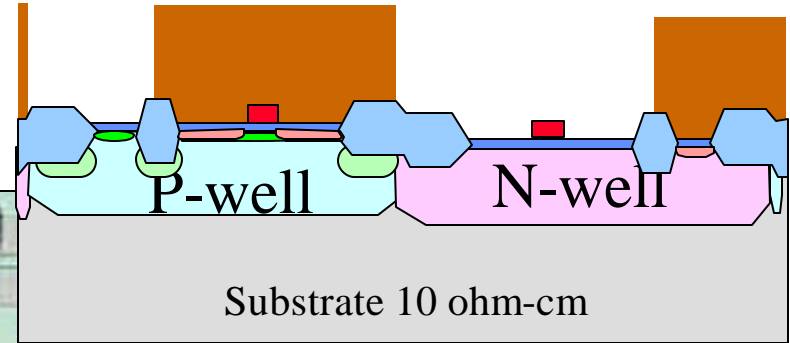
SMALL PMOS  
Column 1 – Row 14

Mag = 10X



**STEP 47 – PH03 LEVEL 7 P-LDD**

**RING OSCILLATOR**



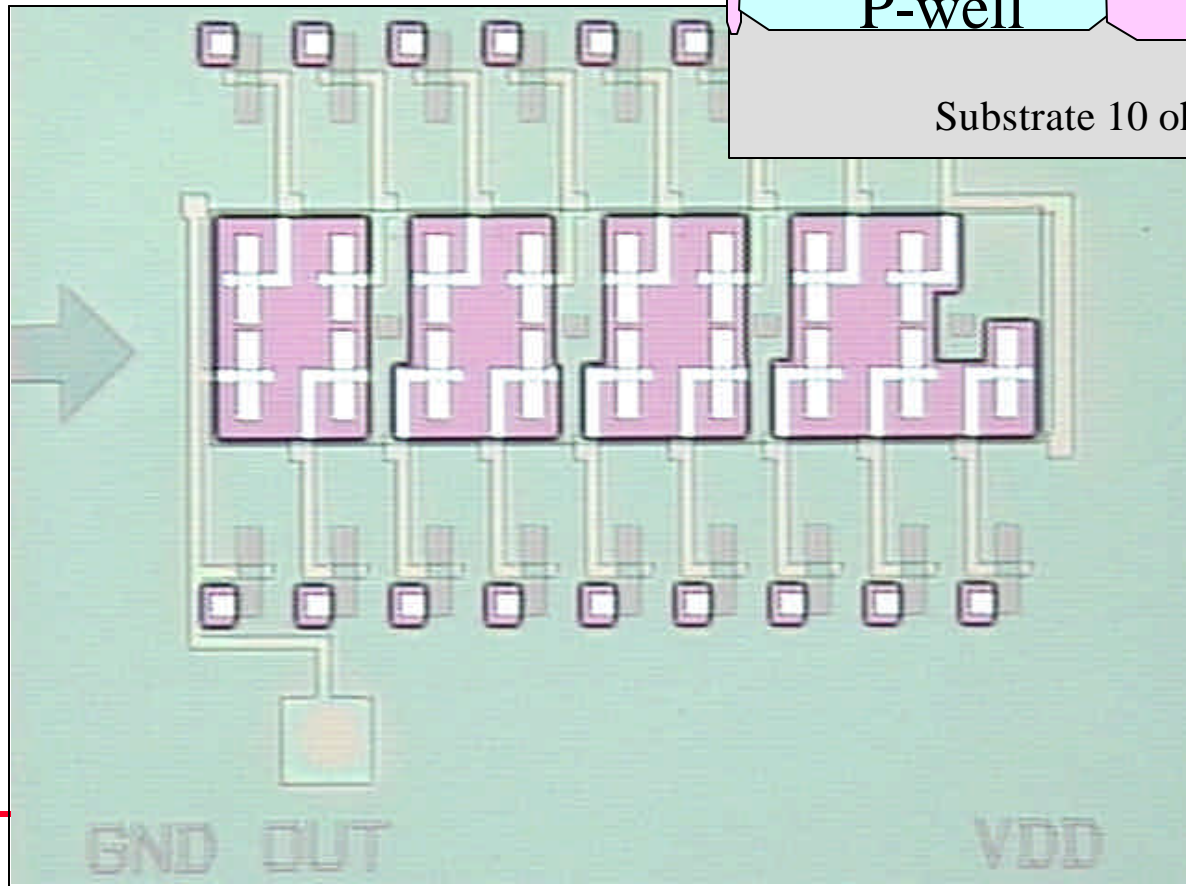
NMOS

PMOS

Column 1 – Row 15

PMOS

NMOS

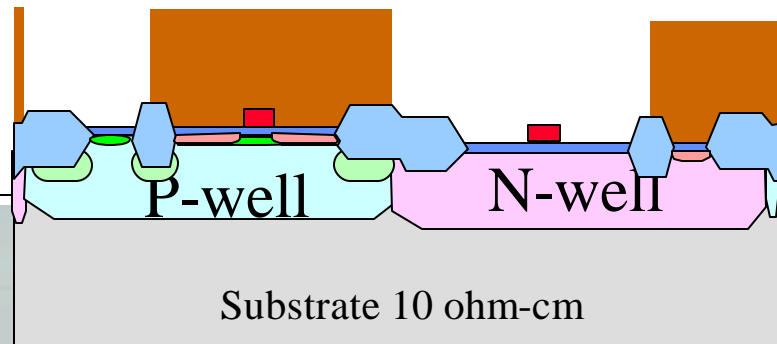


Mag = 10X

**PLAY**

**STEP 47 – PH03 LEVEL 7 P-LDD**

**BIG NMOS / PMOS**



BIG NMOS  
Column 1 – Row 16



BIG PMOS  
Column 1 – Row 17

Mag = 10X

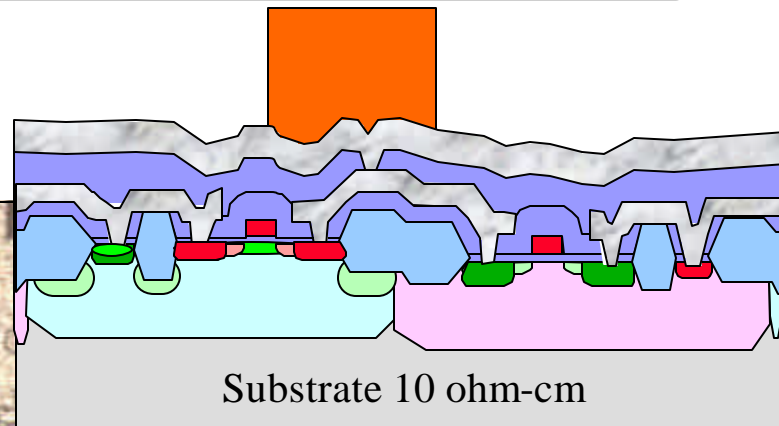
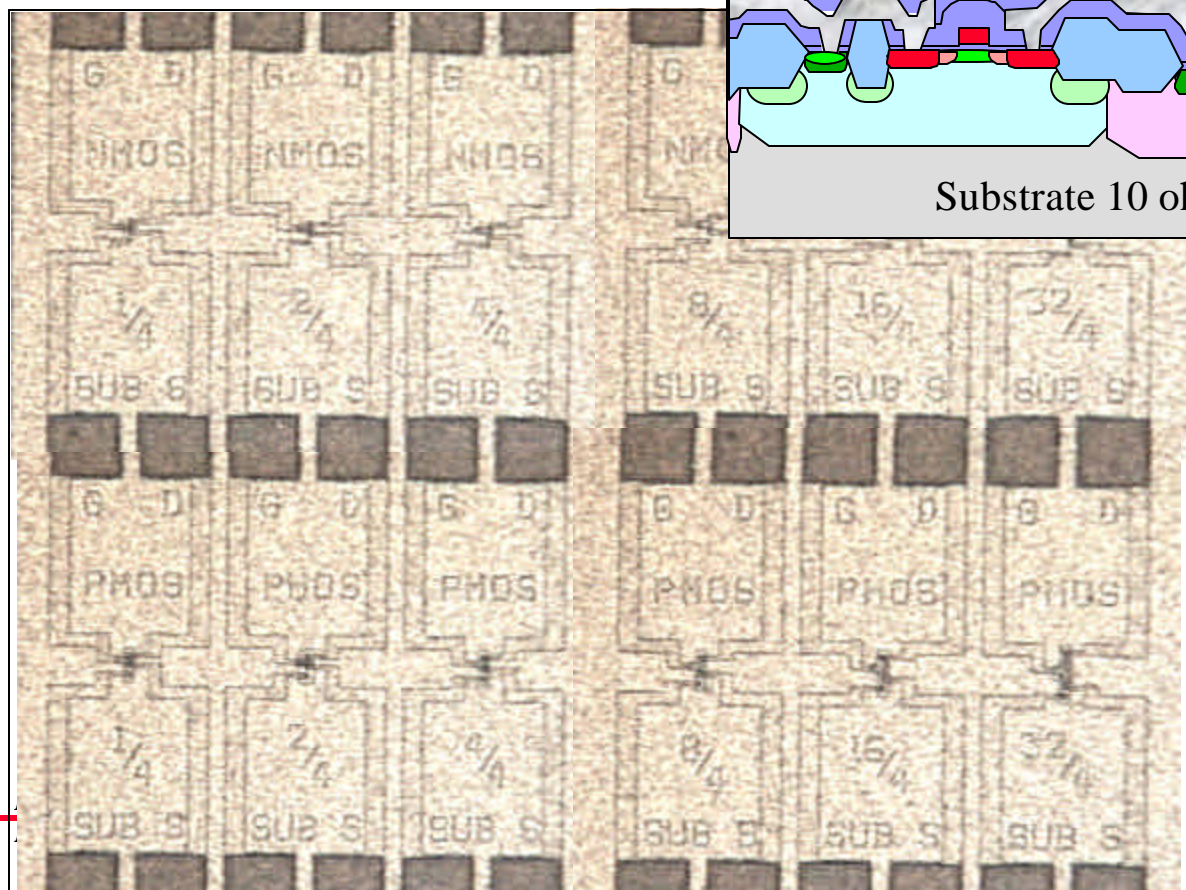
**PLAY**

# STEP 76 – PH03 LEVEL 13 METAL 2

## SMALL NMOS / PMOS

SMALL NMOS  
Column 1 – Row 13

SMALL PMOS  
Column 1 – Row 14



Mag = 10X

PLAY

# STEP 76 – PH03 LEVEL 13 METAL 2

## RING OSCILLATOR

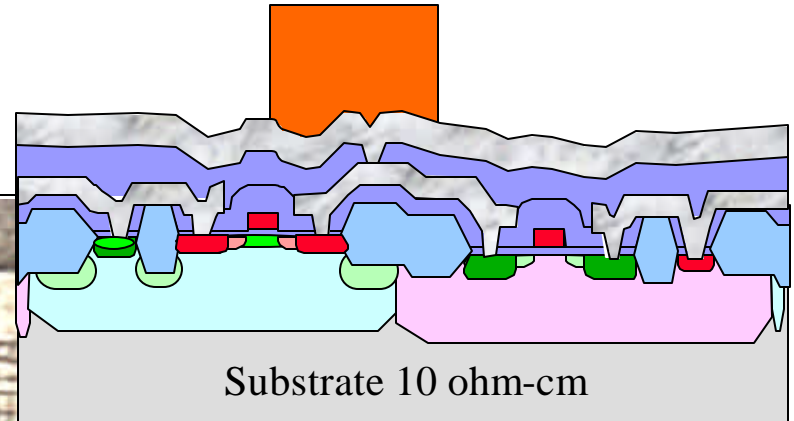
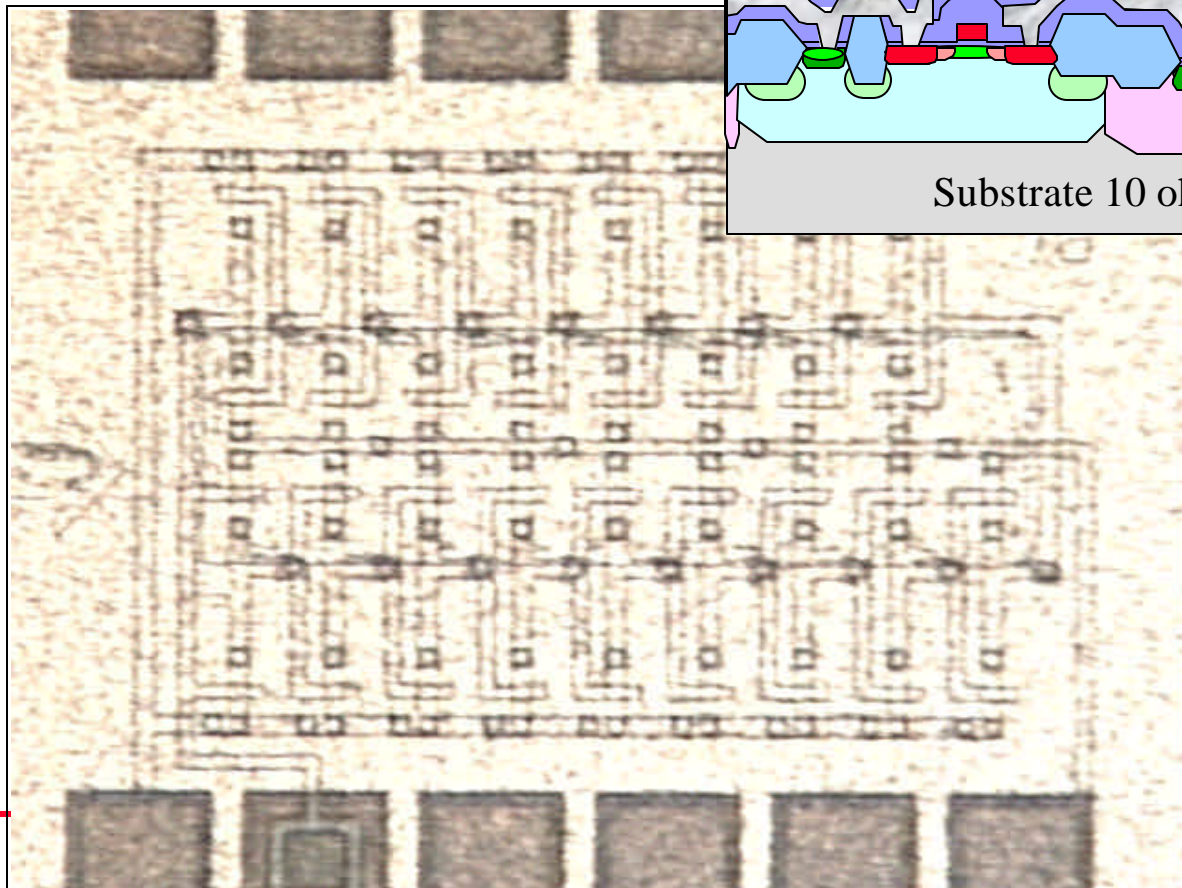
NMOS

PMOS

Column 1 – Row 15

PMOS

NMOS

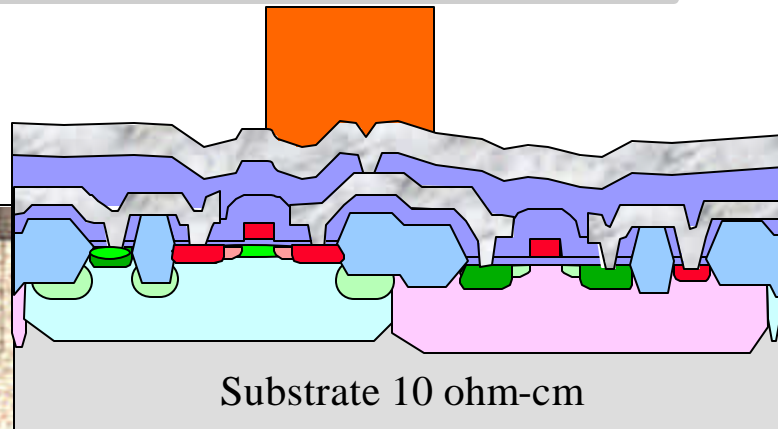


Mag = 10X

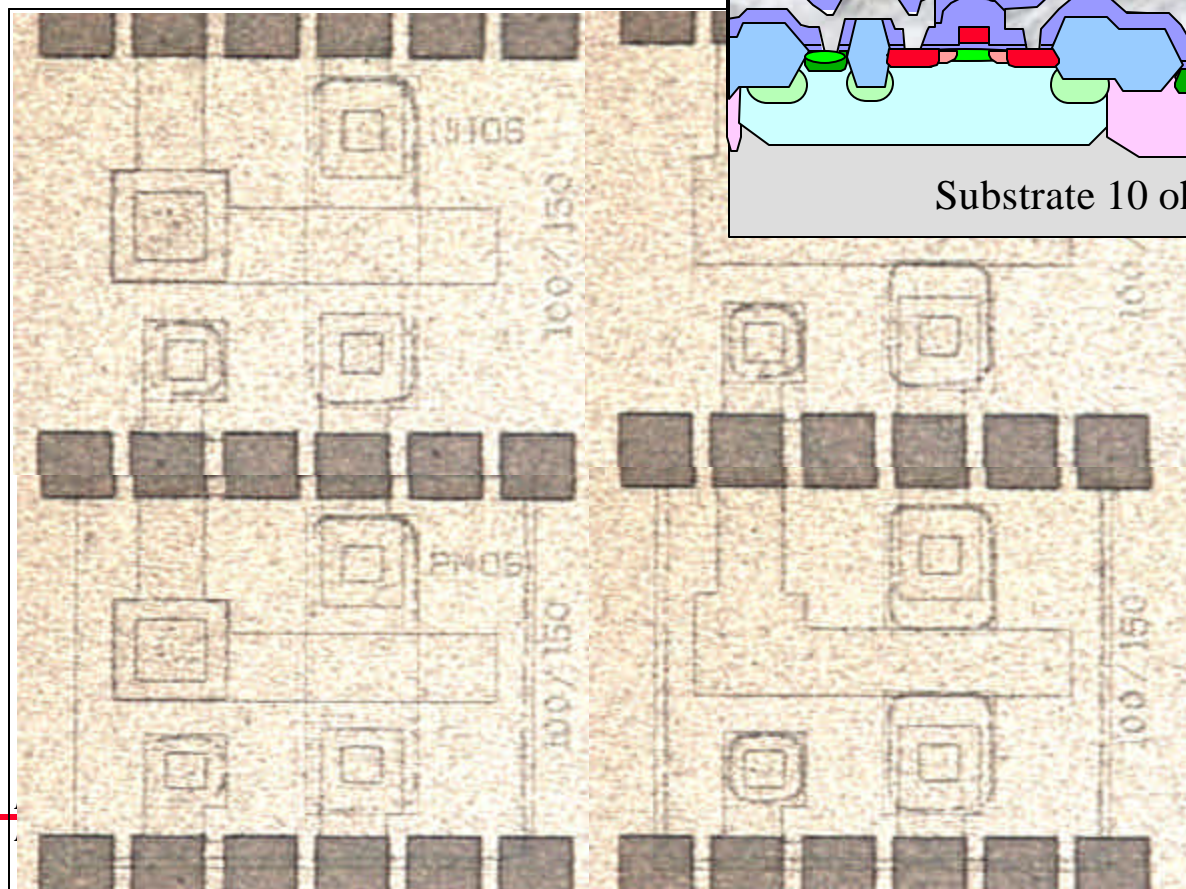
**PLAY**

# STEP 76 – PH03 LEVEL 13 METAL 2

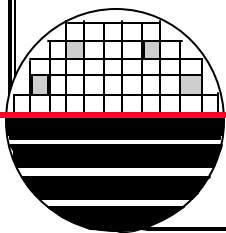
## BIG NMOS / PMOS



BIG NMOS  
Column 1 – Row 16



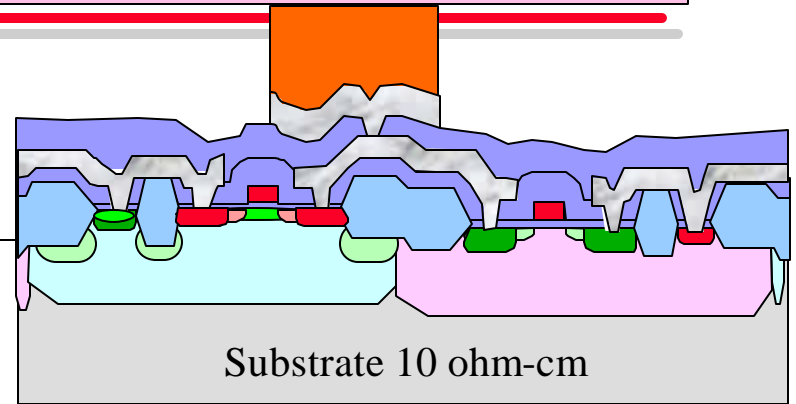
BIG PMOS  
Column 1 – Row 17



Mag = 10X

PLAY

# STEP 77 – ET15 METAL 2 PLASMA ETCH

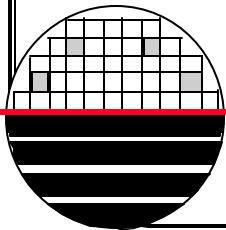


Substrate 10 ohm-cm

## SMALL NMOS / PMOS

SMALL NMOS  
Column 1 – Row 13

SMALL PMOS  
Column 1 – Row 14



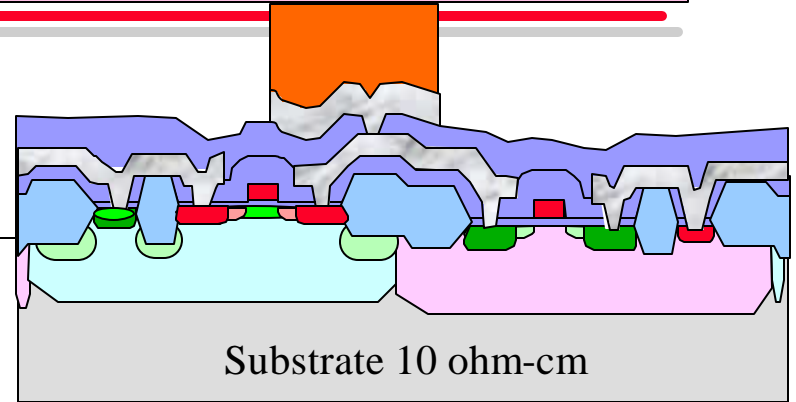
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Mag = 10X

PLAY

# STEP 77 – ET15 METAL 2 PLASMA ETCH

## RING OSCILLATOR



NMOS

PMOS

Column 1 – Row 15

PMOS

NMOS

Mag = 10X

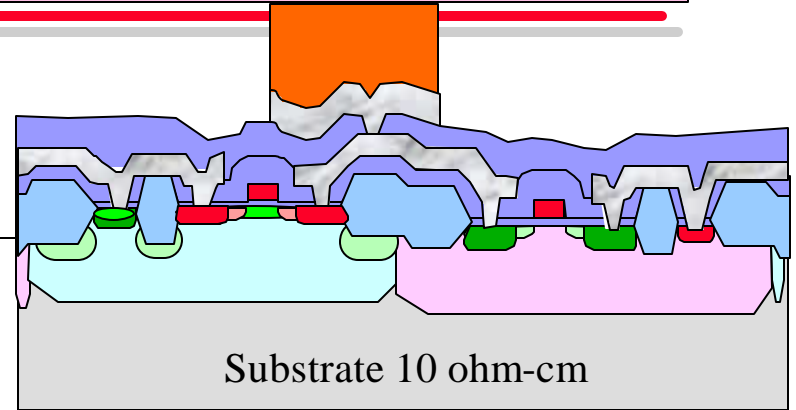
PLAY

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# STEP 77 – ET15 METAL 2 PLASMA ETCH

## BIG NMOS / PMOS



BIG NMOS  
Column 1 – Row 16

BIG PMOS  
Column 1 – Row 17

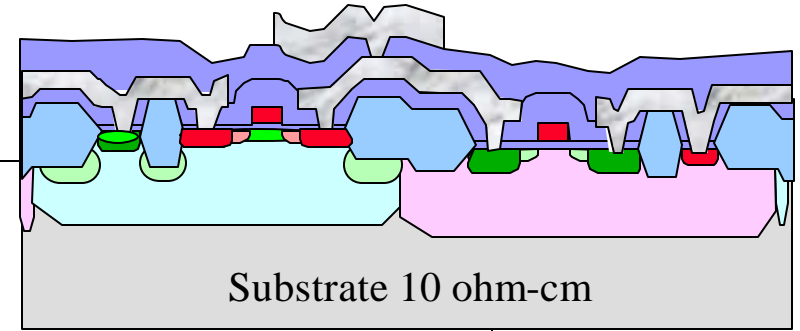
Mag = 10X

PLAY

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# STEP 78 – ET07 RESIST STRIP

## SMALL NMOS / PMOS



SMALL NMOS  
Column 1 – Row 13

SMALL PMOS  
Column 1 – Row 14

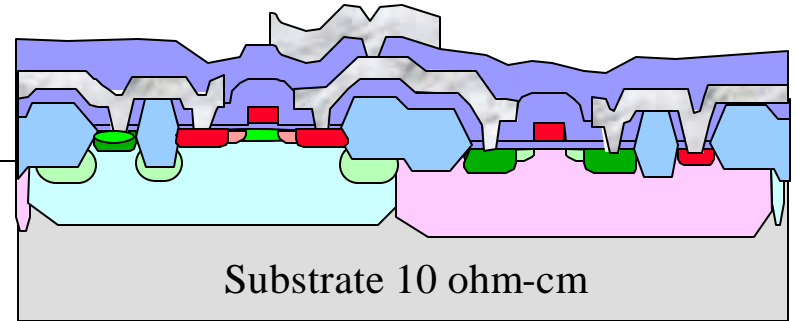
Mag = 10X

PLAY

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# STEP 78 – ET07 RESIST STRIP

## RING OSCILLATOR



NMOS

PMOS

Column 1 – Row 15

PMOS

NMOS

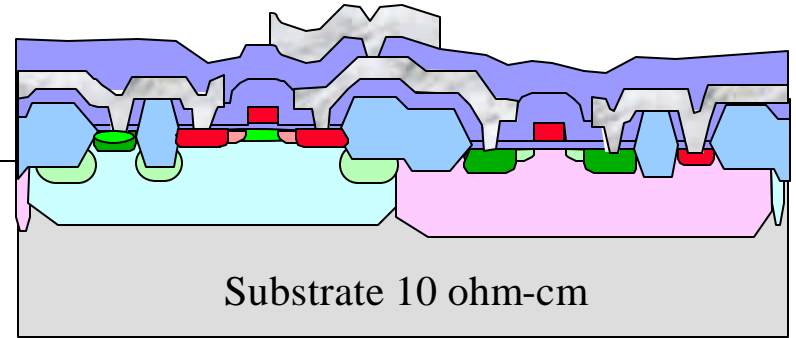
Mag = 10X

PLAY

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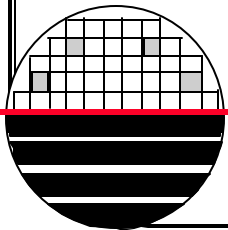
# STEP 78 – ET07 RESIST STRIP

## BIG NMOS / PMOS



BIG NMOS  
Column 1 – Row 16

BIG PMOS  
Column 1 – Row 17



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Mag = 10X

PLAY

